

# *Intrepid Plasma Activation System*



## **Stand-alone automated surface activation tool**

- Load cassette platforms
- SMIF loader
- FOUP loaders

# Primary Features

- Intrepid Equipment's low temperature plasma activation
- Production system with a high-throughput, vacuum transport (estimated throughput of  $\geq$  to 20 wafer pair per hour)
- Automated cassette-to-cassette operation (load cassette platforms, SMIF, or FOUP loaders)
- Contamination-free automated handling.

# Plasma Chamber

## Proprietary plasma activation module

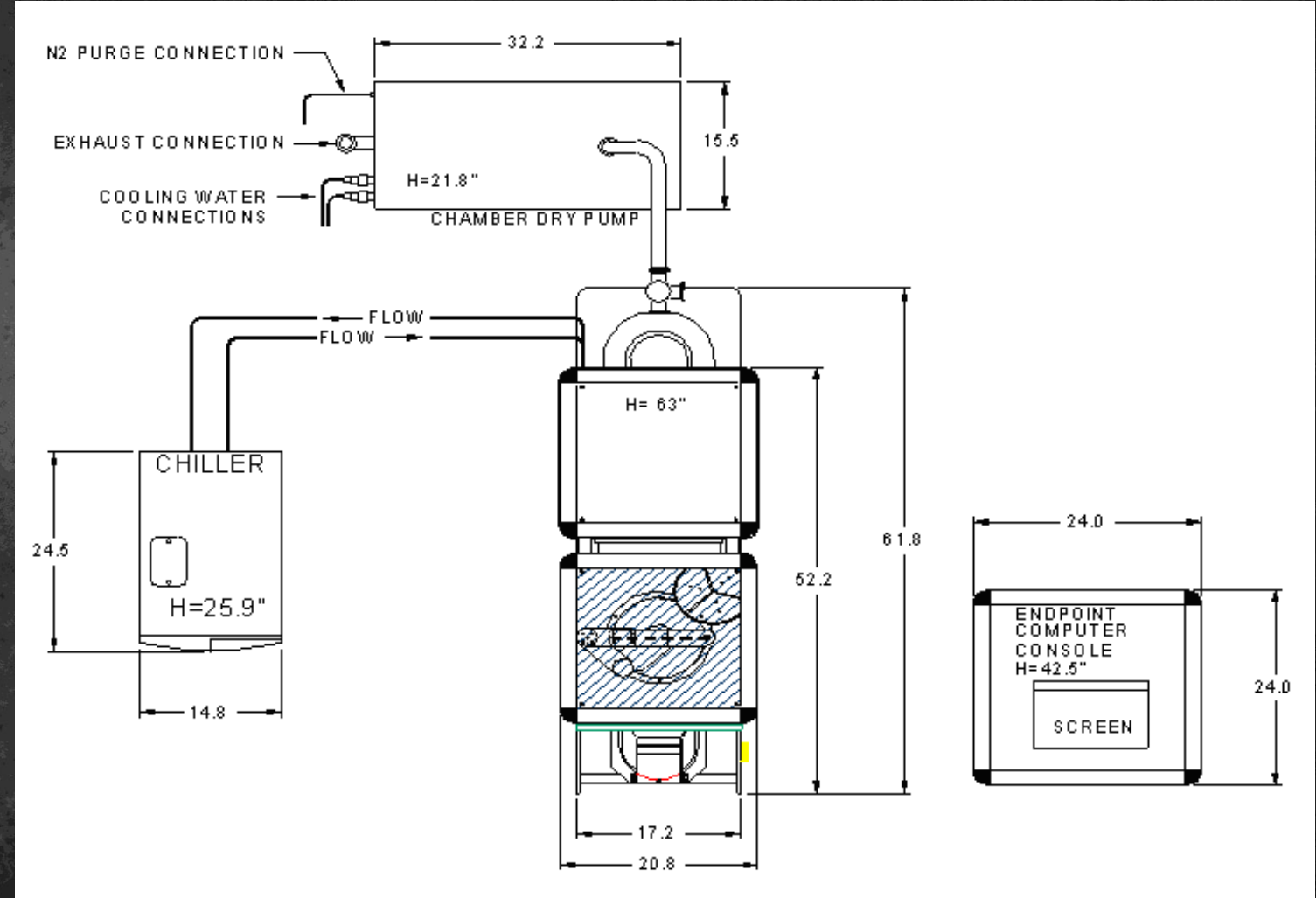
- Proprietary plasma activation source/process
- Fully programmable process, which includes control of all plasma variables: mass flow controllers (4); automated pressure control, RF power control, etc.
- Vacuum system:  $9 \times 10^{-2}$  mbar (standard) and  $9 \times 10^{-3}$  mbar (option with turbo pump)
- Proprietary high energy RF source.



# Intrepid Plasma Activation System Footprint

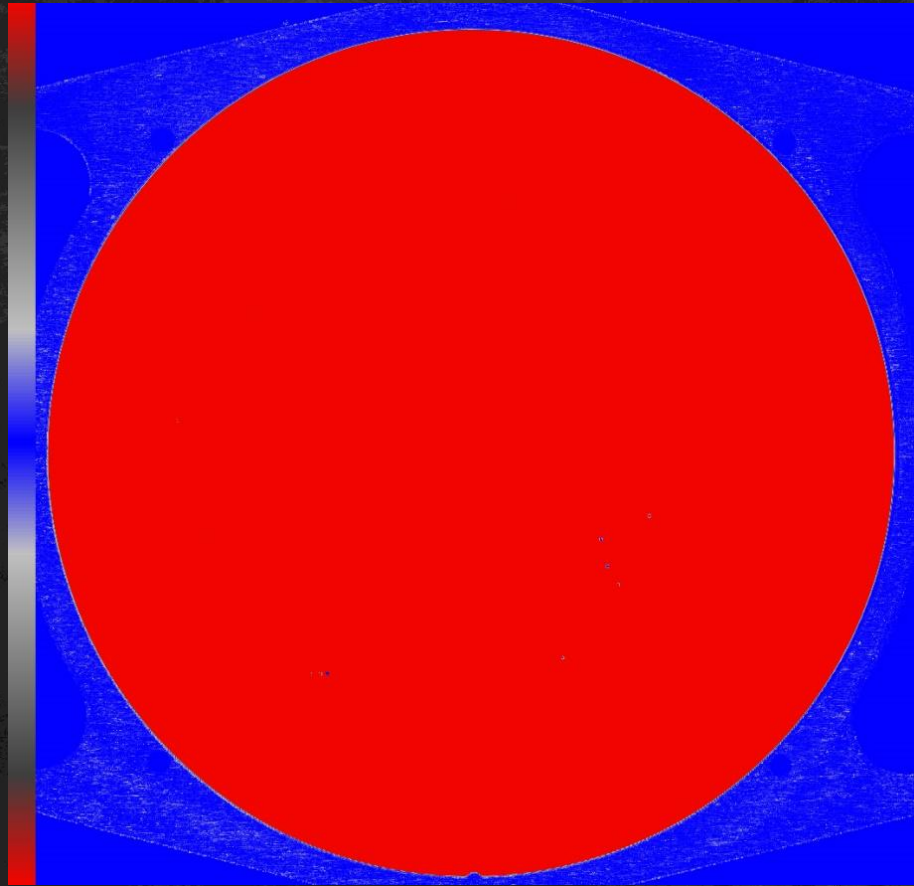


Plasma Activation System

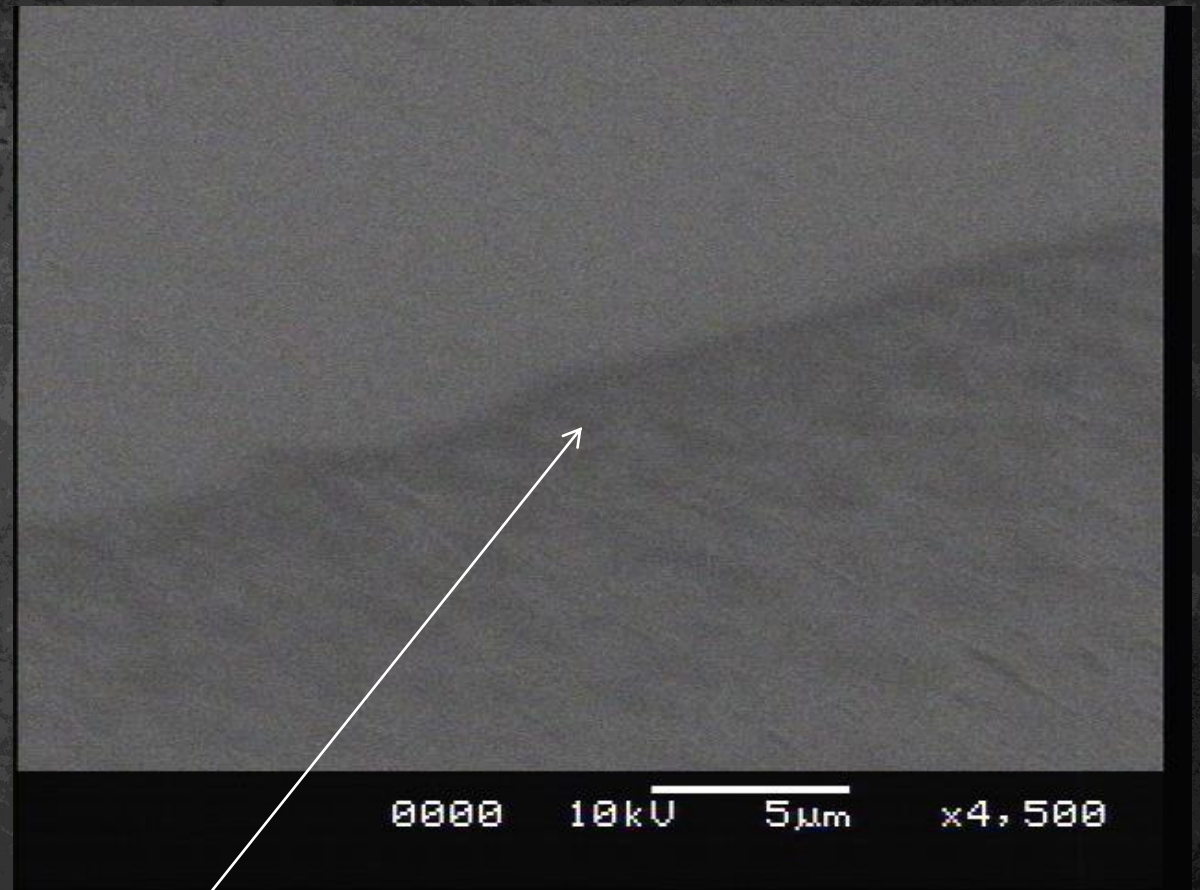


Small Cleanroom Footprint

# Product Example



Scanning Acoustic Microscopy



Shear line showing removed material

*Innovation, throughput, small footprint, simplicity  
= low cost production.*



**Contact Us**

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